US00D360599S

United States Patent [19]

Wada et al.

[11] **Patent Number: Des. 360,599**

[45] **Date of Patent: ** Jul. 25, 1995**

[54] **MEASUREMENT SCANNER FOR SEMI-CONDUCTOR**

[75] Inventors: **Toshihiko Wada**, Musashimurayama; **Tadashi Ohtaka; Nobuyoshi Hashimoto**, both of Katsuta, all of Japan

[73] Assignee: **Hitachi, Ltd.**, Tokyo, Japan

[**] Term: **14 Years**

[21] Appl. No.: **25,210**

[22] Filed: **Jul. 26, 1994**

[30] **Foreign Application Priority Data**

Apr. 15, 1994 [JP] Japan 6-10335

[52] **U.S. Cl.** **D10/75**

[58] **Field of Search** .... D10/46, 75; D13/123, D13/162, 163; D14/102, 107; D24/186; 348/91, 92, 93, 94, 95, 125, 130, 135, 142, 161, 162; 356/380, 386, 387, 121, 237; 360/9.1, 72.1; 382/34; 250/223 B

[56] **References Cited**

U.S. PATENT DOCUMENTS

D. 332,616	1/1993	Hashimoto et al.	D24/186 X
D. 352,910	11/1994	Yamamoto et al.	D10/75

Primary Examiner—Antoine Duval Davis
Attorney, Agent, or Firm—Antonelli, Terry, Stout & Kraus

[57] **CLAIM**

The ornamental design for a measurement scanner for semi-conductor, as shown.

DESCRIPTION

FIG. **1** is a front, top and right side elevational perspective view of measurement scanner for semi-conductor showing our new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a right elevational view thereof;
FIG. **4** is a top plan elevational view thereof;
FIG. **5** is a bottom plan elevational view thereof;
FIG. **6** is a rear elevational view thereof; and,
FIG. **7** is a left elevational view thereof.

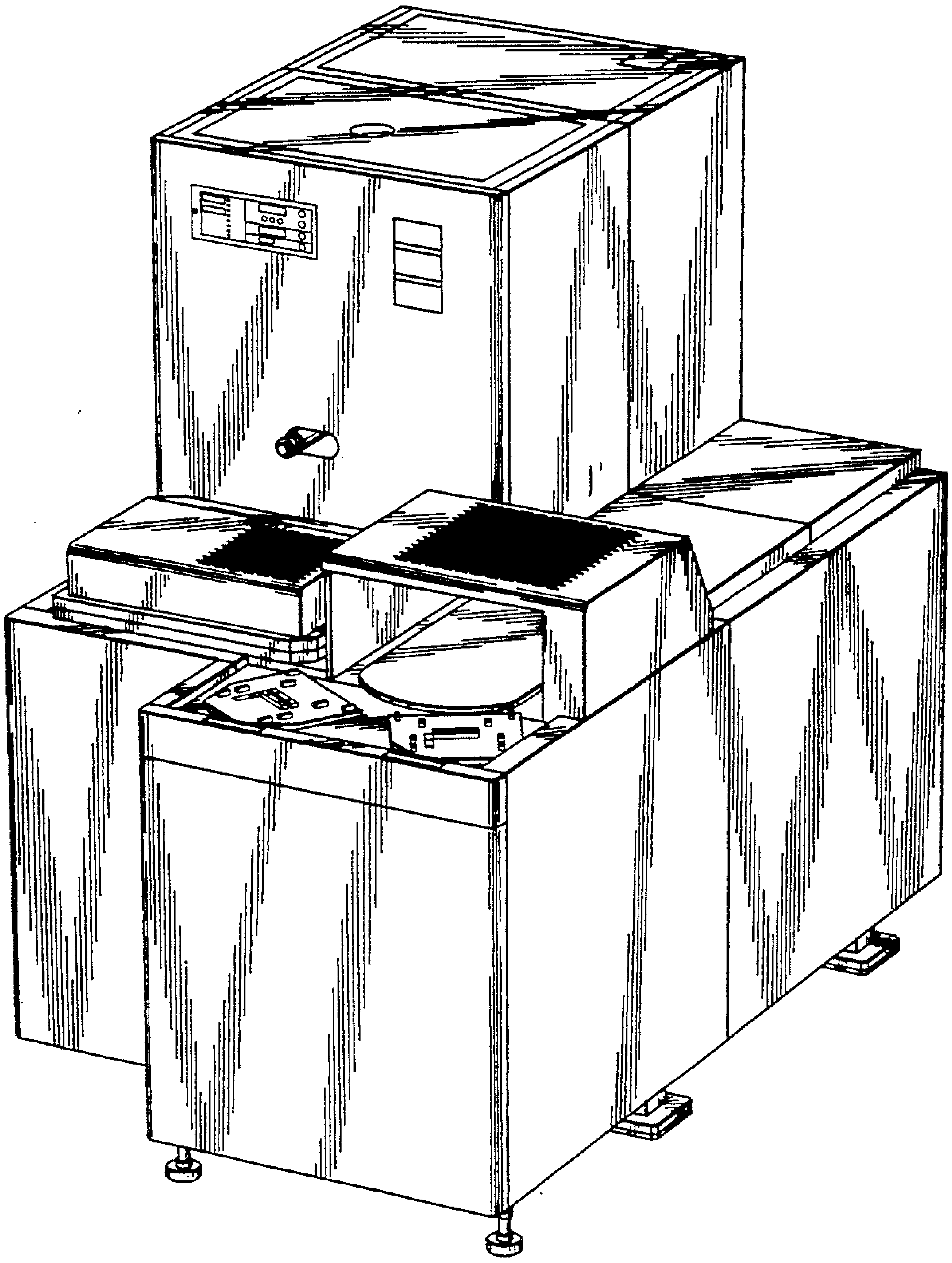


FIG. 1

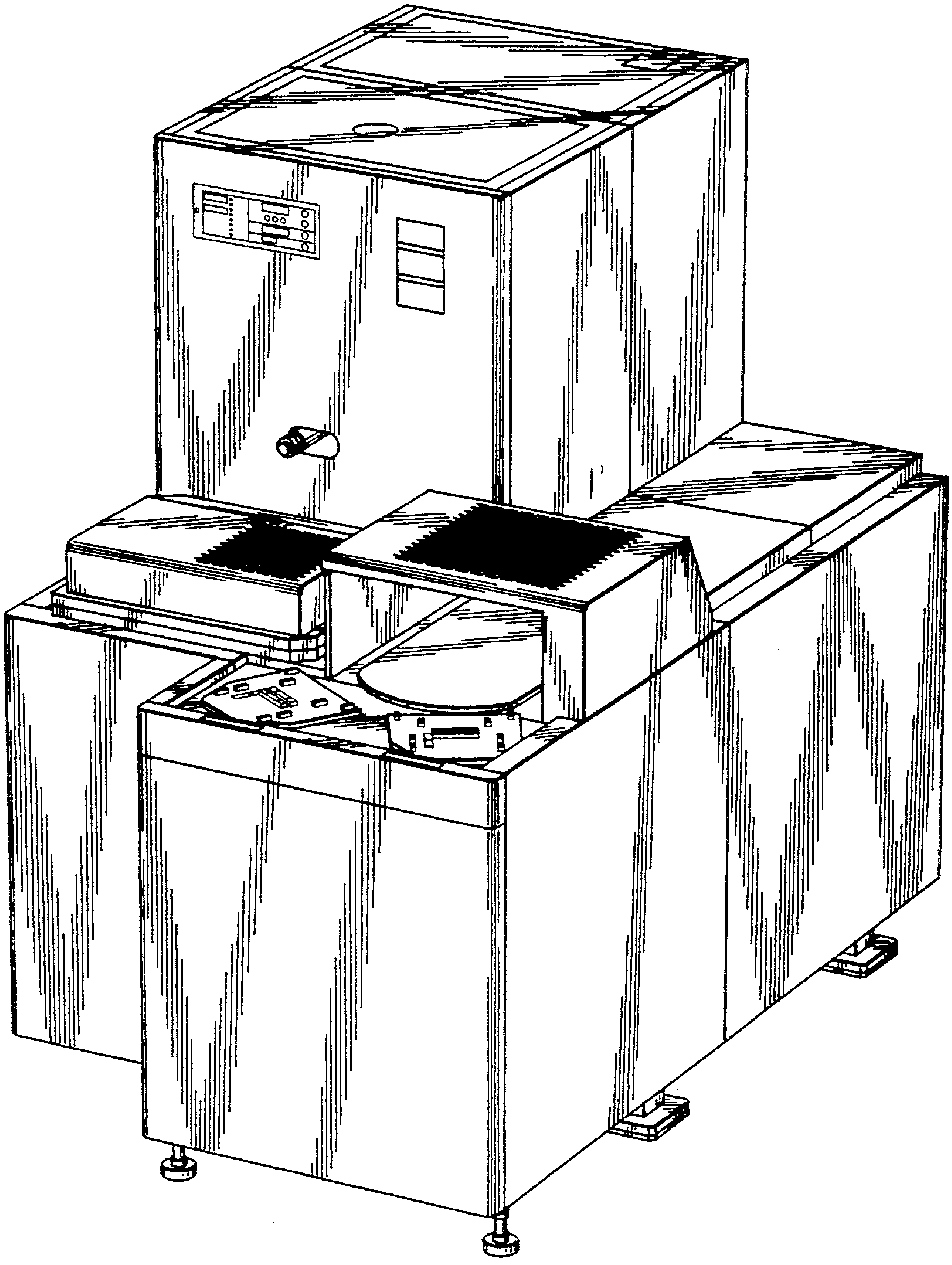


FIG. 3

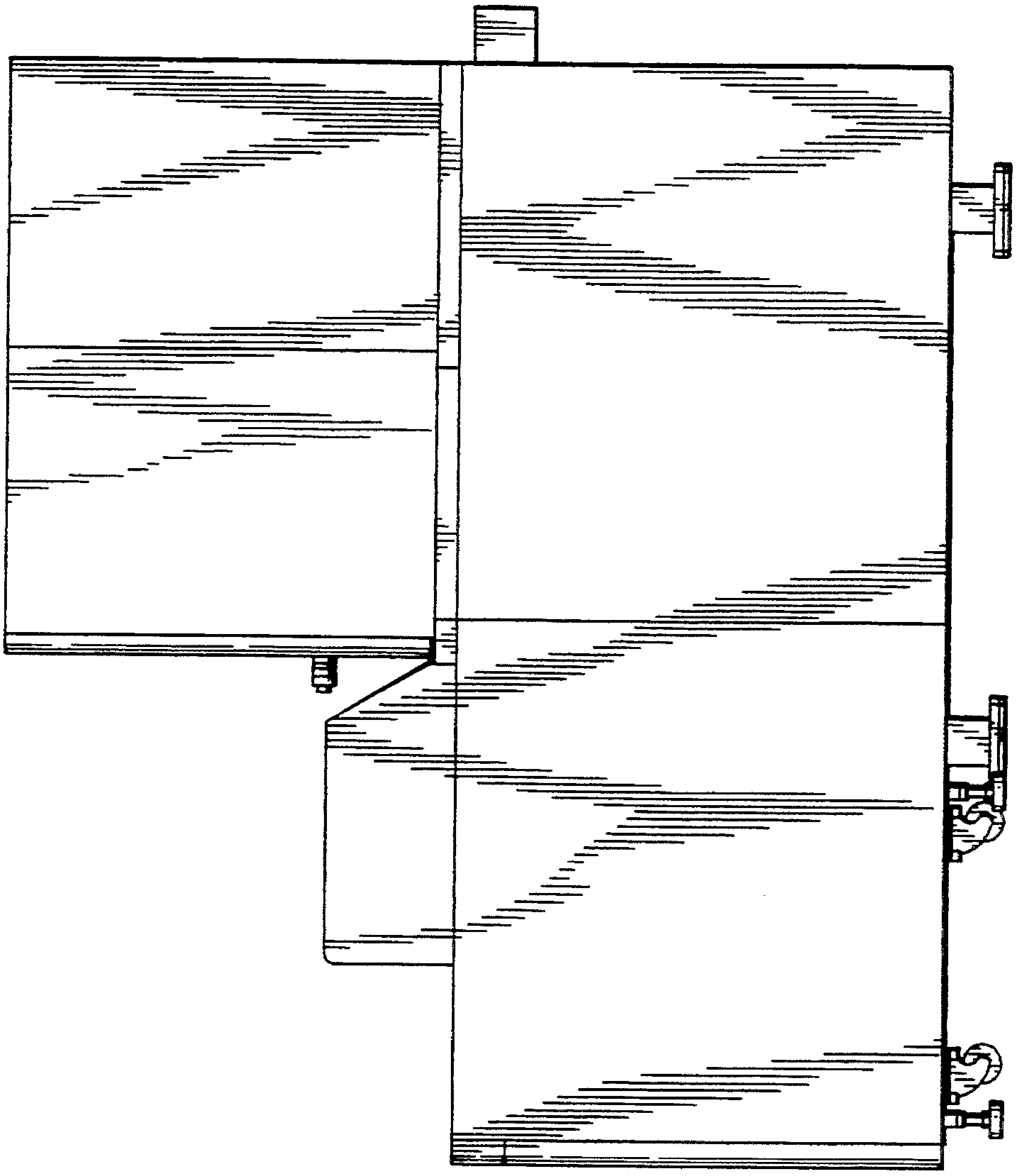
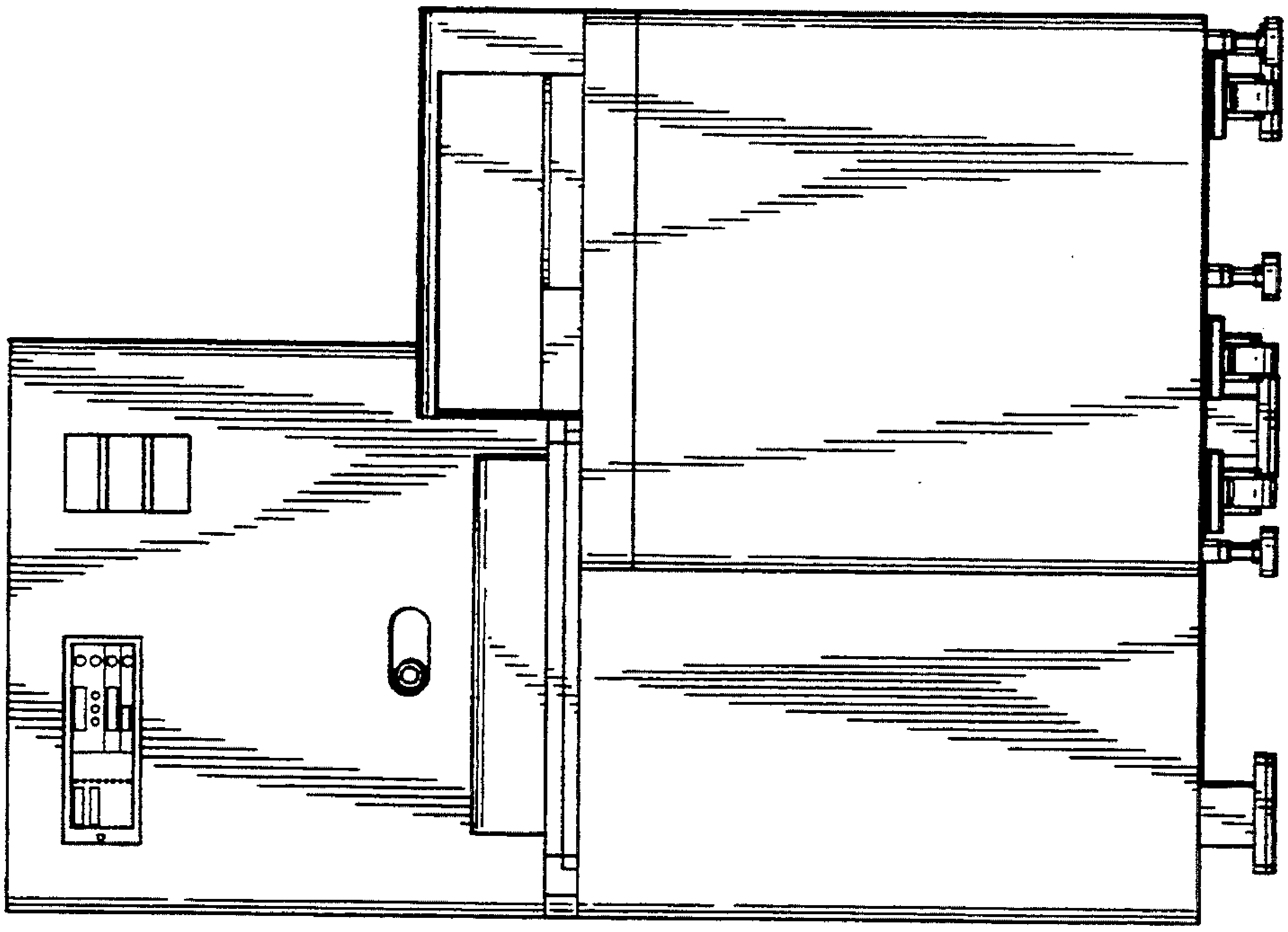


FIG. 2



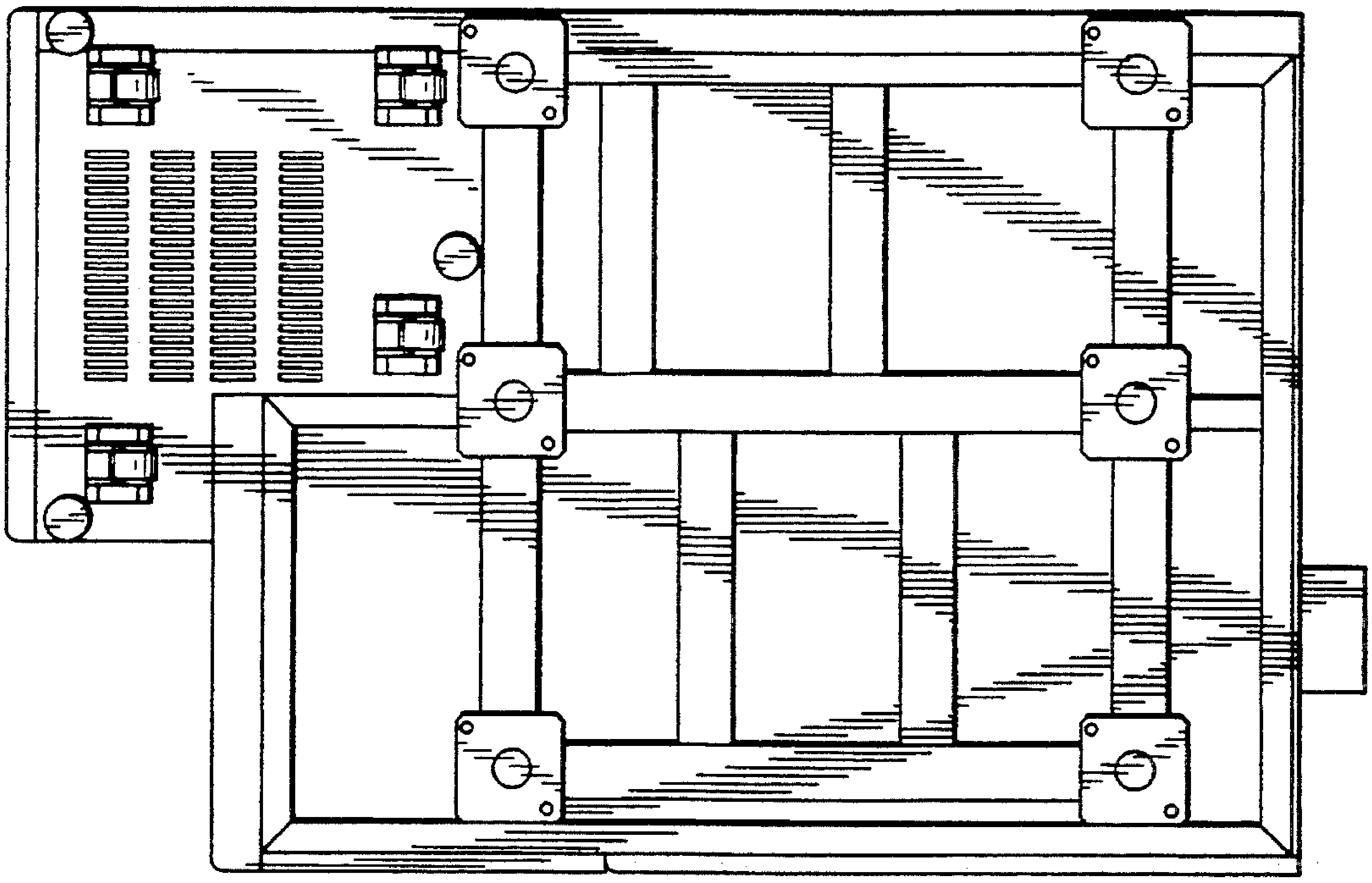


FIG. 5

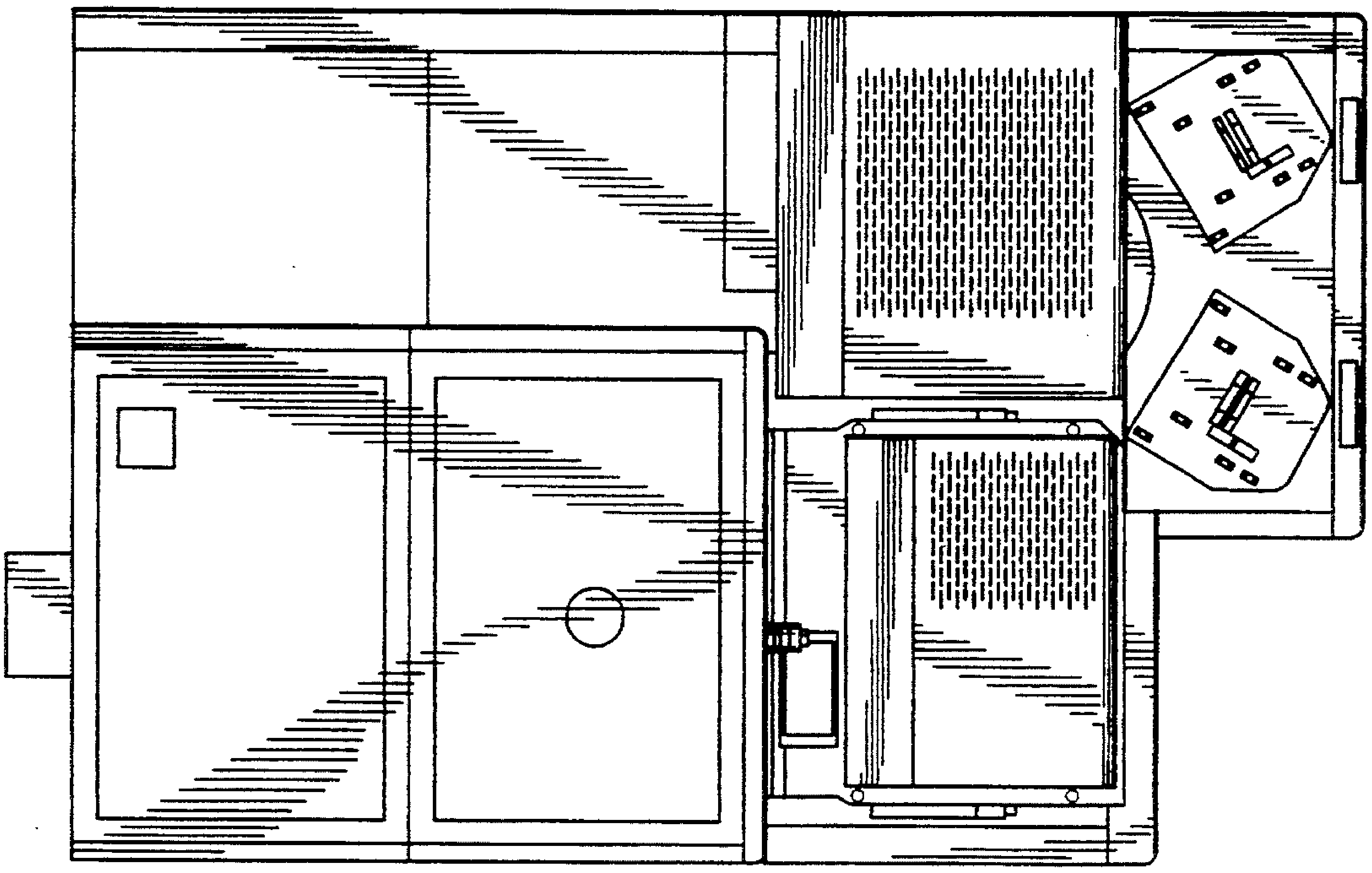


FIG. 4

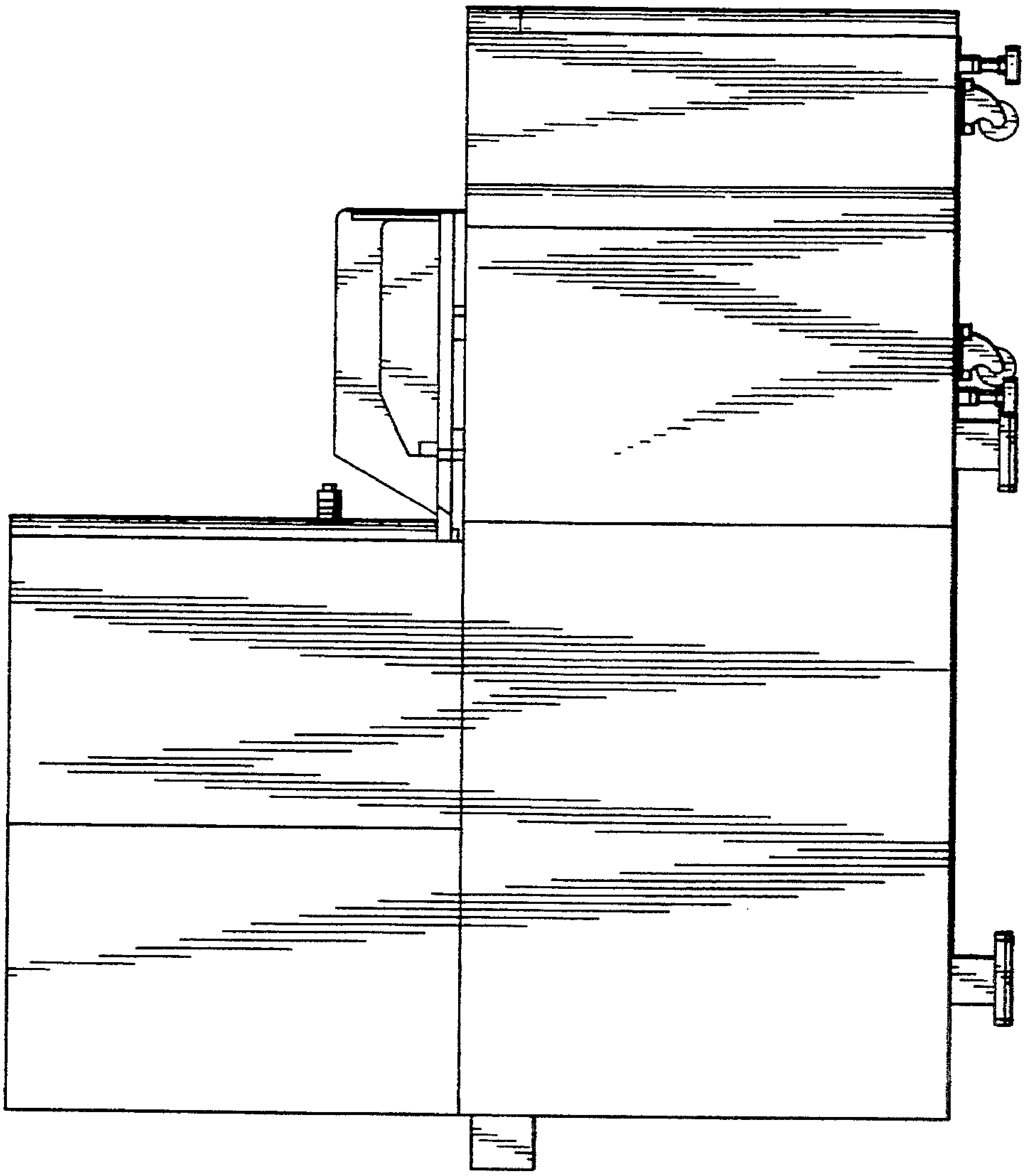


FIG. 7

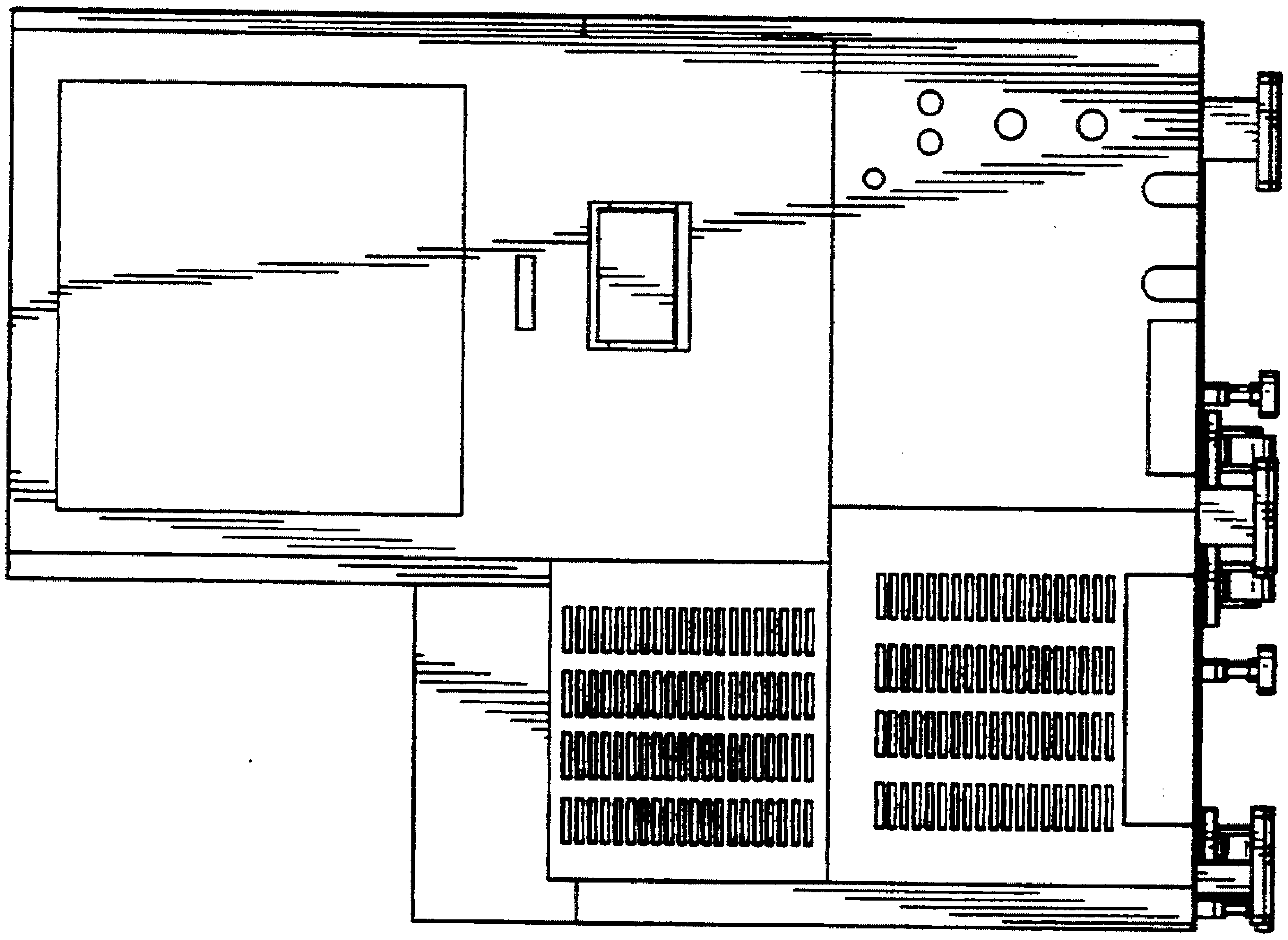


FIG. 6